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Kathi Howard 5/18/06
Kathi Howard Date

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No.: 10/080,496
Filed: February 22, 2002
Patent No.: 6,946,054
Issued: September 20, 2005
Applicant(s): Jozef Brcka
Title: MODIFIED TRANSFER FUNCTION DEPOSITION BAFFLES AND HIGH DENSITY PLASMA IGNITION THEREWITH IN SEMICONDUCTOR PROCESSING

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

ATTN: DECISION AND CERTIFICATE OF CORRECTION
BRANCH OF THE PATENT ISSUE DIVISION

Certificate
MAY 25 2006
of Correction

**REQUEST FOR CERTIFICATE OF CORRECTION OF PATENT
FOR PTO MISTAKE (37 CFR §1.322 (a))**

Sir:

Attached in duplicate form, is Form PTO-1050, with at least one copy being suitable for printing. The errors below and on Form PTO-1050 were typographical errors which occurred through the fault of the U.S. Patent and Trademark Office ("PTO"), and correction thereof does not involve such changes in the patent as would constitute new matter or would require reexamination.

The exact column and line number where the errors are shown in the patent are as follows:

MAY 26 2006

Column 1, lines 16-17 read "...energy is inductively coupled through a dielectric material hat is protected by a slotted deposition baffle to energize a..." and should read – ...energy is inductively coupled through a dielectric material that is protected by a slotted deposition baffle to energize a... –.

Column 2, line 59 reads "...magnetic flux normal to the surface o the baffle is increased." and should read – ...magnetic flux normal to the surface of the baffle is increased. –.

Column 3, line 4 reads, "...many atoms hay to be ionized to produce ions and electrons..." and should read – ...many atoms have to be ionized to produce ions and electrons... –.

Column 3, line 9 reads, "...makes it difficult to ignite a plasma by an electric field ram..." and should read – ...makes it difficult to ignite a plasma by an electric field from... –.

Column 3, line 11 reads, "...to produce strange electric fields in its vicinity can result in..." and should read – ...to produce stronger electric fields in its vicinity can result in... –.

Column 6, line 54 reads, "...field B_a lie in the e planes. These flux lines loop through the..." and should read – ...field B_a lie in these planes. These flux lines loop through the... –.

Column 8, line 51 reads, "...Bridges 34 across the chevron shaded slots 31a of deposition..." and should read – ...Bridges 34 across the chevron shaped slots 31a of deposition...–.

Column 8, lines 55-56 read, "...side of the deposition baffle 30a, as shown in FIG. 3C. thereby restricting the return current paths by avoiding paths..." and should read – ...side of the deposition baffle 30a, as shown in FIG. 3C, thereby restricting the return current paths by avoiding paths...–.

Column 10, line 28 reads, "...concept o adding the blades 37 to the slots 31 can be..." and should read – ...concept of adding the blades 37 to the slots 31 can be...–.

Column 11, line 19 reads, "...longitudinal ends o the blades 37a that extend the full length..." and should read – ...longitudinal ends of the blades 37a that extend the full length...–.

Column 15, CLAIM 4, line 60 reads, "...bounding the slots block line-of-sight path through the..." and should read – ...bounding the slots block line-of-sight paths through the... –.

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10/10/2006

Column 16, CLAIM 10, line 36 reads, "...plasma processing space from 0 watts to up to level..." and should read – ...plasma processing space from 0 watts to up to a level... –.

Column 16, CLAIM 10, line 40 reads, "...upon ignition o the plasma, revising the RF power and..." and should read – ...upon ignition of the plasma, revising the RF power and... –.

Column 16, CLAIM 12, line 51 reads, "...the ramping o the DC power includes ramping the power..." and should read – ...the ramping of the DC power includes ramping the power... –.

Column 16, CLAIM 12, line 56 reads, "...pressure s approximately 20 mTorr." and should read – ...pressure is approximately 20 mTorr. –.

Column 17, CLAIM 24, lines 63-64 read, "...a controller programmed to control the apparatus to ignite plasma within the plasma processing space according..." and should read – ...a controller programmed to control the apparatus to ignite a plasma within the plasma processing space according... –.

Column 17, CLAIM 24, line 66 reads, "...energizing the oil with RF power of at least 300 wafts,..." and should read – ...energizing the coil with RF power of at least 300 watts,... –.

Column 18, CLAIM 24, line 2 reads, "...plasma processing space from 0 watts to up to level..." and should read – ...plasma processing space from 0 watts to up to a level... –.

Column 18, CLAIM 26, line 22 reads, "...pressure s approximately 20 mTorr." and should read – ...pressure is approximately 20 mTorr. –.

Please send the certificate to:

Joseph R. Jordan, Esq.
Wood, Herron & Evans, L.L.P.
2700 Carew Tower
Cincinnati, Ohio 45202

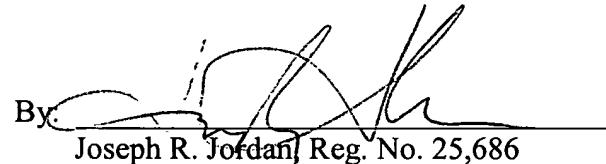
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Since all of the above errors are due to typos made by the USPTO, a check for the correction has not been included, however, if there is any further charge or credit due, please use Deposit Account No. 23-3000.

Respectfully submitted,

WOOD, HERRON & EVANS, L.L.P.

By 
Joseph R. Jordan, Reg. No. 25,686

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UNITED STATES PATENT AND TRADEMARK OFFICE
CERTIFICATE OF CORRECTION

PATENT NO. : 6,946,054

DATED : September 20, 2005

INVENTOR(S) : Jozef Brcka

It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Column 1, lines 16-17 read "...energy is inductively coupled through a dielectric material hat is protected by a slotted deposition baffle to energize a..." and should read - ...energy is inductively coupled through a dielectric material that is protected by a slotted deposition baffle to energize a... -.

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MAILING ADDRESS OF SENDER:

Wood, Herron & Evans, L.L.P.
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